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PATENT  
Customer No. 22,852  
Attorney Docket No. 7553.0019-01

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

|                             |   |                          |
|-----------------------------|---|--------------------------|
| In re Application of:       | ) |                          |
|                             | ) |                          |
| Chishio KOSHIMIZU et al.    | ) | Group Art Unit: 1763     |
|                             | ) |                          |
| Application No.: 10/675,966 | ) | Examiner: P. Hassanzadeh |
|                             | ) |                          |
| Filed: October 2, 2003      | ) |                          |
|                             | ) |                          |
| For: PLASMA PROCESSING      | ) | Confirmation No. 6290    |
| APPARATUS AND PLASMA        | ) |                          |
| PROCESSING METHOD           | ) |                          |

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**AMENDMENT**

In reply to the Office Action mailed July 2, 2004, the period for response having been extended to January 3, 2005 (January 2, 2005 being a Saturday) by a Petition for Extension of Time - Three Months and appropriate fee payment, please amend the application as follows.

**Amendments to the Claims** are reflected in the listing of claims in this paper.

**Remarks** follow the amendment section of this paper.